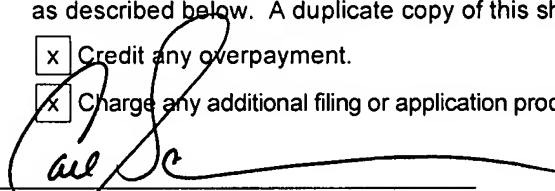




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AMENDMENT TRANSMITTAL LETTER				Docket No. ISH-0227	
Application No. 10/523,976-Conf. #1124		Filing Date February 8, 2005		Examiner M. T. Rachuba	
				Art Unit 3723	
Applicant(s): Toshihiro TSUCHIYA					
Invention: WAFER POLISHING METHOD AND APPARATUS					
TO THE COMMISSIONER FOR PATENTS					
Transmitted herewith is an amendment in the above-identified application.					
The fee has been calculated and is transmitted as shown below.					
CLAIMS AS AMENDED					
	Claims Remaining After Amendment	Highest Number Previously Paid	Number Extra Claims Present	Rate	
Total Claims	2	- 20 =	0	x 50.00	0.00
Independent Claims	2	- 3 =	0	x 200.00	0.00
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					
Other fee (please specify):					
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT:					0.00
<input checked="" type="checkbox"/> Large Entity <input type="checkbox"/> Small Entity					
<input checked="" type="checkbox"/> No additional fee is required for this amendment.					
<input type="checkbox"/> Please charge Deposit Account No. _____ in the amount of \$ _____. A duplicate copy of this sheet is enclosed.					
<input type="checkbox"/> A check in the amount of \$ _____ to cover the filing fee is enclosed.					
<input type="checkbox"/> Payment by credit card. Form PTO-2038 is attached.					
<input checked="" type="checkbox"/> The Director is hereby authorized to charge and credit Deposit Account No. <u>18-0013</u> as described below. A duplicate copy of this sheet is enclosed.					
<input checked="" type="checkbox"/> Credit any overpayment.					
<input checked="" type="checkbox"/> Charge any additional filing or application processing fees required under 37 CFR 1.16 and 1.17.					
 _____ Lee Cheng				Dated: <u>June 12, 2007</u>	
Attorney/Agent Reg. No.: 40,949					
Carl Schaukowitch Attorney/Agent Reg. No.: 29,211					
RADER, FISHMAN & GRAUER PLLC 1233 20th Street, N.W. Suite 501 Washington, DC 20036 (202) 955-3750					



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Toshihiro TSUCHIYA

Application No.: 10/523,976

Filed: February 8, 2005

For: WAFER POLISHING METHOD AND APPARATUS

Attorney Docket No.: ISH-0227

Examiner: M. T. Rachuba

Art Unit: 3723

Confirmation No.: 1124

AMENDMENT AFTER FINAL REJECTION UNDER 37 C.F.R. §1.116

Mail Stop AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

I. INTRODUCTORY COMMENTS

In response to the final Office Action dated April 12, 2007, please amend the above-identified application as set forth below.

Claims 2 and 3 are pending in the application. By this Amendment, claims 1, 4 and 5 are canceled without prejudice or disclaimer.

Applicants express their appreciation for the Examiner's allowance of claims 2 and 3. It is respectfully submitted that the application is now in condition for allowance.

II. AMENDMENTS TO THE DRAWINGS

(There are no amendments to the drawings)

III. AMENDMENTS TO THE SPECIFICATION

(There are no amendments to the specification)